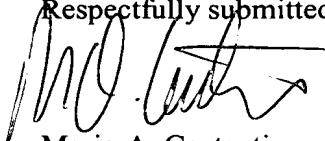


- ☒ 3. The reference(s) was/were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.
- ☒ 4. In accordance with 37 CFR §1.98(a)(2)(i), copies of any U.S. patents and patent application publications are not attached.

Respectfully submitted,



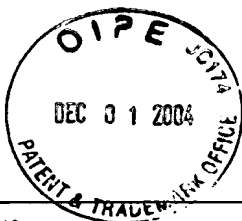
Mario A. Costantino
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MAC/ccs

Date: December 1, 2004

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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>

Sheet 1 of 1

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 109325.01		APPLICATION NO. 10/791,810	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT(S) Yuji IMAI			
				FILING DATE March 4, 2004		GROUP 2851	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
		4,908,656	03-13-1990	Suwa et al.			
		5,815,594	09-29-1998	Tanaka			
		5,252,414	10-12-1993	Yamashita et al.			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
		SPIE Vol. 1464 Integrated Circuit Metrology, Inspection, and Process Control V (1991), "Use of diffracted light from latent images to improve lithography control", K.C. Hickman et al., pages 245-257.					
EXAMINER				DATE CONSIDERED			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Date: December 1, 2004